

ISSM2020 Program Schedule At-A-Glance

December 15 (Day-1)		December 16 (Day-2)	
RoomA	RoomB	RoomA	RoomB
8:50 Opening Remarks, Conference Outline, Program Schedule		8:50 Keynote Speech 3 Prof. Takayasu Sakurai/The Univ. of Tokyo Session Chair: Hiroyuki Mori, Renesas Electronics	
9:10 Tutorial Speech 1 (in Japanese) Prof. Yasuyuki Shirai / Tohoku University Session Co-chairs: Dr. Ayako Shimazaki, Toshiba Nanoanalysis Dr. Keiji Horioka		9:30 Break(10mins)	
9:50 Break (5mins)		9:40 Keynote Speech 4 Dr. Vivek Jain / Maxim Integrated Session Chair: Toshiyuki Uchino, Kokusai Electric	
9:55 Tutorial Speech 2 (in Japanese) Prof. Koji Eriguchi / Kyoto University Session Co-chairs: Dr. Ayako Shimazaki, Toshiba Nanoanalysis Dr. Keiji Horioka		10:20 Break (5mins)	
10:35 Break (10mins)		10:25 Keynote Speech 5 Prof. Takeshi ABE / Kyoto Univ. Session Chair: Dr. Shin-ichi Imai, Hitachi High-Tech Solutions	
10:45 Keynote Speech1 Masataka Osaki / NVIDIA Japan Session Chair: Dr. Shin-ichi Imai, Hitachi High-Tech Solutions		11:05 Break (5mins)	
11:25 Break (5mins)		11:10 Keynote Speech 6 Akira Minamikawa / Omdia Session Chair: Dr. Hiroshi Akahori, KIOXIA Corporation	
11:30 Keynote Speech 2 Dr. Nicky Lu / ETRON Session Chair: Shuichi Inoue, ATONARP		11:50 Lunch Break & Exhibitor Presentation 40mins	
12:10 Lunch Break & Exhibitor Presentation 40mins		12:30 AI Contest * SEM Image Classification AI Algorithm Contest * Semiconductor Manufacturing Fab Data AI utilization Idea Contest Session Chair: Dr. Shin-ichi Imai, Hitachi High-Tech Solutions	
12:50 EDTM202-Invited Session Chair: Dr. Ayako Shimazaki, Toshiba Nanoanalysis		13:30 Break (10mins)	
13:10 Break (10mins)		13:40 Keynote Speech 7 Dr. Salvatore Coffa / ST Microelectronics Session Chair: Yasutoshi Okuno, SCREEN Semiconductor Solutions	
13:20 Session A-1: Process/Material Optimization (PO)-1 Session Co-chairs: Dr. Tsuyoshi Moriya, Tokyo Electron Dr. Shin-ichi Imai, Hitachi High-Tech Solutions		14:20 Break (10mins)	
13:40 Session B-1: Worker and WIP Control (WC) & Manufacturing Strategy (MS) Session Co-chairs: Katsutoshi Ozawa, OMRON Takatoshi Yasui, Tower Partners Semiconductor		14:30 Session A-4: Process Monitoring & Control Method (PM)-3 Session Co-chairs: Yuji Yamada, KIOXIA Dr. Kazuhito Matsukawa, SUMCO	
14:00 Session A-2: Process/Material Optimization (PO)-2 & Process Monitoring & Control Method (PM)-1 Session Co-chairs: Dr. Hiroyuki Inoue, Texas Instruments Japan Masahiro Shimbo, ON Semiconductor		14:50 Session B-4: Yield & Defect Control (YD)-2 Session Co-chairs: Takahiro Tsuchiya, United Semiconductor Japan Shinsuke Mizuno, Applied Materials Japan	
14:20 Author's interview by Paper & Break		15:10 Session B-2: Intelligent Data Management (ID)-1 & Material Informatics (MI) & New Gas, New Liquid, and New Resist Technologies (NM) Session Co-chairs: Kazuki Yokota, Renesas Electronics Dr. Kenji Watanabe, SanDisk	
14:40 Session A-3: Process Monitoring & Control Method (PM)-2 & Ultraclean Technology (UT) Session Co-chairs: Isamu Namose, OMRON Takayuki Hisamatsu, Sony Semiconductor Manufacturing		15:30 Session B-3: Yield & Defect Control (YD)-1 Session Co-chairs: Masami Aoki, KLA-Tencor Japan Akimasa Soyano, JSR	
15:00 Session A-4: Process Monitoring & Control Method (PM)-3 Session Co-chairs: Yuji Yamada, KIOXIA Dr. Kazuhito Matsukawa, SUMCO		15:50 Author's interview by Paper & Break	
15:40 Author's interview by Paper & Break		16:10 Session A-5: Process Monitoring & Control Method (PM)-4 & Intelligent Data Management (ID)-2 Session Co-chairs: Masami Aoki, KLA-Tencor Japan Dr. Hiroyuki Inoue, Texas Instruments Japan	
16:00 Author's interview by Paper & Break		16:30 Session B-5: Final Manufacturing & Integrated Package (FM) Session Co-chairs: Kazunori Kato, Advanced Interface Technology Dr. Kenji Miyake, PMT	
16:20 Session A-3: Process Monitoring & Control Method (PM)-2 & Ultraclean Technology (UT) Session Co-chairs: Isamu Namose, OMRON Takayuki Hisamatsu, Sony Semiconductor Manufacturing		16:50 Author's interview by Paper & Break	
16:40 Session B-3: Yield & Defect Control (YD)-1 Session Co-chairs: Masami Aoki, KLA-Tencor Japan Akimasa Soyano, JSR		17:10 Author's interview by Paper & Break	
17:00 Session A-4: Process Monitoring & Control Method (PM)-3 Session Co-chairs: Yuji Yamada, KIOXIA Dr. Kazuhito Matsukawa, SUMCO		17:30 Author's interview by Paper & Break	
17:20 Author's interview by Paper & Break		17:50 Award & Networking	
17:40 Author's interview by Paper & Break		18:00 Break (10mins)	
18:00 Break (10mins)		18:10 Networking	
18:10 Networking		19:00 Award & Networking	
19:00		19:00	